

Title (en)

Apparatus and method for depositing a substance on a rotating surface.

Title (de)

Vorrichtung und Methode zum Auftragen eines Werkstoffes auf eine rotierende Oberfläche.

Title (fr)

Appareillage et méthode pour déposer une substance sur une surface tournante.

Publication

**EP 0661387 A3 19961218 (EN)**

Application

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Priority

US 17558693 A 19931230

Abstract (en)

[origin: EP0661387A2] This invention relates to temperature control during material deposition and, more particularly, to controlling temperature of a substance experiencing high thermal energy fluxes while being deposited on a rotating surface. In accordance with an embodiment of the invention for depositing a substance, there is provided a deposition chamber for containing heated constituents of the substance and a mandrel assembly, which includes a mandrel mounted on a base. The mandrel assembly is rotatable on an axis, and the mandrel thereof has a surface in said chamber. <IMAGE>

IPC 1-7

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IPC 8 full level

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